

# Simulations of a Planar Silicon Tunnel Field-Effect Transistor

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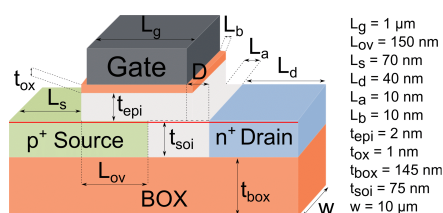
As planar metal-oxide-semiconductor field-effect transistors (MOSFETs) are scaled to the nanometre regime, their sub-threshold swing (SS) characteristics significantly degrade. This degradation causes a high power consumption limiting the performance of low power transistors in digital applications. Tunnelling-FETs (TFETs) are considered a promising solution to overcome the poor performance of MOSFETs in the sub-threshold region (leakage current ( $I_{\text{OFF}}$ ) and SS) [1] by surpassing the fundamental limit of MOSFETs of 60 mV/dec at room temperature. The on-current ( $I_{\text{ON}}$ ) of TFETs depends on the distance between the conduction and valence band because the  $I_{\text{ON}}$  arises from a band-to-band tunnelling (BTBT) process with low efficiency. Thus the TFETs suffer from a low  $I_{\text{ON}}$  [2]-[3]. In Ref. [3], a new device structure is proposed to overcome the low  $I_{\text{ON}}$  issue by adding an extra layer between the gate-dielectric and the p-i-n junction in order to increase the tunnelling area. The aim of this work is to investigate and optimise the performance of a TFET based on the experimental device [3]. The n-type Si TFET has a gate length of 1  $\mu\text{m}$  shown in Fig. 1. The epi-layer and the SOI have an intrinsic doping of  $1.0 \times 10^{15} \text{ cm}^{-3}$ , the p-type source has a concentration of  $3.7 \times 10^{19} \text{ cm}^{-3}$  and the n-type drain of  $2.7 \times 10^{20} \text{ cm}^{-3}$ . The work function of the metal gate is 4.8 eV. All the simulations have been performed using Silvaco ATLAS [6] accounting for both the local and non-local BTBT, for the band-gap narrowing, and the thermionic emission transport model. Fig. 2 shows the  $I_{\text{D}}\text{-}V_{\text{G}}$  characteristics at a drain bias of 1.0 V comparing simulations with experimental data with a very good agreement at large gate biases. The simulations allow to optimise the device architecture since  $I_{\text{OFF}}$  increases dramatically with a drain-to-gate distance (D) while  $I_{\text{ON}}$  shows a minimal change.

**Acknowledgment:** This work is supported by the Spanish Government and FEDER funds (TEC2014-59402-JIN), by the Spanish Government (TIN2013-41129-P) and also by Xunta de Galicia and FEDER funds (GRC 2014/008).

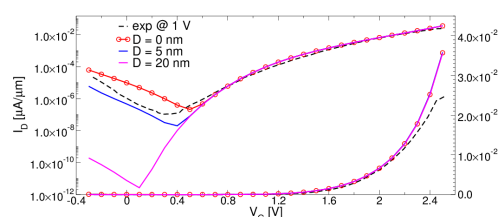
## References

- [1] P. K. Singh et al., IJCET, vol. 4, no. 3, pp. 2088-2091, 2014.
- [2] J. L. Padilla et al., IEEE TED, vol. 59, no. 12, pp. 3205-3211, 2012.
- [3] Y. Morita et al., Solid-State Electronics, vol. 102, pp. 82-86, 2014.
- [4] Silvaco. (2016) ATLAS User's Manual.

## Figures



**Figure 1:** Schematic of the TFET with the corresponding dimensions. The z-direction is assumed to be a 10  $\mu\text{m}$  wide.



**Figure 2:**  $I_{\text{D}}\text{-}V_{\text{G}}$  characteristics on both linear (right) and logarithmic (left) scales at a high drain bias of 1.0 V.